## What is claimed is:

1. An array substrate for use in an IPS-LCD device, comprising:

a plurality of double-layered gate lines on a substrate, wherein the doublelayered gate lines are comprised of first and second layers that overlap each other;

a plurality of data lines over the substrate, wherein each data line is perpendicular to each double-layered gate line, and wherein each pair of double-layered gate and data lines defines a pixel area;

a double-layered common line on the substrate, wherein the double-layered common line is parallel with and spaced apart from the double-layered gate line, and wherein the double-layered common line is comprised of first and second layers that wherein each other;

a plurality of protrusions extending from first layer of the double-layered gate lines, wherein each protrusion has a hole in a central portion thereof;

a plurality of common electrodes extending from the second layer of the double-layered common line and parallel with the data line;

a common-connecting line perpendicular to and connecting the common electrodes with each other;

a plurality of pixel electrodes spaced apart from and parallel with the said common electrodes, wherein each pixel electrode is located between a pair of common electrodes and corresponds to at least one common electrode;

first and second pixel-connecting lines parallel with the double-layered common line and respectively connecting the pixel electrodes with each other at respective first and second ends of the pixel electrodes, wherein the second pixel-connecting line overlaps a portion of the double-layered common line to form a storage

capacitor; and

a switching element electrically located in one corner of the pixel area and connected with the double-layered gate and data lines, the switching element contacting the first pixel-connecting line and supplying voltage to the said pixel electrodes.

- 2. The array substrate according to claim 1, further comprising: a gate insulation layer covering the substrate and the double-layered gate lines and the double-layered common lines.
- 3. The array substrate according to claim 1, further comprising: a passivation layer formed over the swiching element and having a drain contact hole and an etching hole.
- 4. The array substrate according to claim 3, wherein the etching hole is formed over a portion of each protrusion.
- 5. The array substrate according to claim 3, wherein the switching element includes a source electrode that extends from the data line; a double-layered gate electrode that extends from the double-layered gate line; a drain electrode that contacts the first pixel-connecting line through the drain contact hole; an active layer over the double-layered gate electrode; and ohmic contact layer interposed between the active layer and the source and drain electrodes.

- 6. The array substrate according to claim 5, wherein the source and drain electrodes and the data lines are made of the metallic material selected from a group consisting of chromium (Cr), aluminum (Al), aluminum alloy (Al alloy), molybdenum (Mo), tantalum (Ta), tungsten (W), and antimony (Sb).
- 7. The array substrate according to claim 1, wherein the double-layered common line is made of the same material of the double-layered gate lines and formed in the same layer of the double-layered gate lines.
- 8. The array substrate according to claim 1, wherein the protrusions extended from the first layer of the double-layered common line are located on both sides of the storage capacitor.
- 9. The array substrate according to claim 1, wherein each protrusion has a quadrilateral shape.
  - 10. The array substrate according to claim 1, wherein each protrusion has a quadrilateral-shaped hole in a central portion of the protrusion.
  - 11. The array substrate according to claim 1, wherein the first layers of the double-layered gate and common lines include aluminium (Al).
  - 12. The array substrate according to claim 1, wherein the second layers of the double-layered gate and common lines are made of Molybdenum (Mo)

- 13. The array substrate according to claim 1, wherein the second layers of the double-layered gate and common lines are made of Chrome (Cr).
- 14. A method of fabricating an array substrate for use in an IPS-LCD device, comprising:

depositing a first metallic material on a substrate;

patterning the first metallic material to form a first gate electrode, a first gate line, a first common line, and a plurality of protrusions, wherein each protrusion has a hole in a central portion thereof and extends from the first common line, and wherein the first gate electrode extends from the first gate line;

depositing a second metallic material on the substrate and on the patterned first metallic material;

patterning the second metallic material to form a second gate electrode, second gate line, second common line, a common-connecting line, and a plurality of common electrodes, wherein the first and second gate electrodes overlap each other to form a double-layered gate electrode, wherein the first and second common lines overlap each other to form a double-layered common line, and wherein the first and second gate lines overlap each other to form a double-layered gate line;

forming a gate insulation layer on the substrate and on the patterned second metallic material;

forming an active layer and an ohmic contact layer sequentially on the gate insulation layer and over the double-layered gate electrodes;

depositing a third metallic material on the ohmic contact layer and on the gate

insulation layer;

forming a data line, a source electrode, and a drain electrode by patterning the third metallic material, wherein the source and drain electrodes are over the double-layered gate electrodes, and wherein the data line is perpendicular to both the double-layered gate lines and double-layered common lines;

forming a passivation layer on the patterned third metallic layer and on the gate insulation layer, wherein the passivation layer has a drain contact hole to the drain electrode, and an etching hole over each protrusion;

depositing a transparent conductive material on the passivation layer having the drain contact hole and the etching hole; and

forming a plurality of pixel electrodes and first and second connecting lines.

- 15. A method of fabricating an array substrate according to calim 14, further comprising: forming a channel region by patterning a portion of the ohmic contact layer between the source and drain electrodes.
  - 16. A method of fabricating an array substrate according to claim 14, wherein each pair of double-layered gate lines and data lines defines a pixel area.
  - 17. A method of fabricating an array substrate according to claim 14, wherein the double-layered common line is parallel with and spaced apart from the double-layered gate line.

- 18. A method of fabricating an array substrate according to claim 14, wherein a plurality of the common electrodes are parallel with the data line.
- 19. A method of fabricating an array substrate according to claim 14, wherein the common-connecting line is perpendicular to and connects the plural common electrodes with each other.
- 20. A method of fabricating an array substrate according to claim 14, wherein a plurality of the pixel electrodes are spaced apart from and parallel with the issaid common electrodes.
- 21. A method of fabricating an array substrate according to claim 14, wherein each pixel electrode is located between the pair of common electrodes and corresponds to each common electrode.
  - 22. A method of fabricating an array substrate according to claim 14, wherein the first and second pixel-connecting lines are parallel with the double-layered common line and respectively connect the pixel electrodes to each other at respective first and second ends of the pixel electrodes.
  - 23. A method of fabricating an array substrate according to claim 14, wherein the second pixel-connecting line overlaps a portion of the double-layered common line to form a storage capacitor.

- 24. The array substrate according to claim 23, wherein the protrusions extended from the first common line are located on both sides of the storage capacitor.
- 25. A method of fabricating an array substrate according to claim 14, wherein the double-layered gate electrode, the active layer, the ohmic contact layer, the source electrode and the drain electrode comprise a thin film transistor that is located near the crossing of a double-layer gate line and data line.
- A method of fabricating an array substrate according to claim 14, wherein the third metallic material is selected from a group consisting of chromium (Cr), aluminum (Al), aluminum alloy (Al alloy), molybdenum (Mo), tantalum (Ta), tungsten (W), and antimony (Sb).
- 27. A method of fabricating an array substrate according to claim 14, wherein the double-layered common line is made of the same material as the double-layered gate lines and formed in the same layer as the double-layered gate lines.
  - 28. A method of fabricating an array substrate according to claim 14, wherein each protrusion has a quadrilateral shape.
  - 29. A method of fabricating an array substrate according to claim 14, wherein each protrusion has a quadrilateral-shaped hole in a central portion thereof.

- 31. A method of fabricating an array substrate according to claim 14, wherein the second metallic material is selected from a group consisting of molybdenum (Mo), chrome (Cr) and tungsten (W).
  - 32. A liquid crystal display device, comprising:

first and second substrates;

a plurality of data lines on the first substrate;

a plurality of gate lines on the first substrate perpendicular to the data lines;

wherein a pixel region is defined by the intersection of one of the gate lines and

one of the data lines;

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a common line in the pixel region parallel to the gate lines;

a plurality of common electrodes in the pixel region parallel to the data lines and extending from the common line;

a thin film transistor in the pixel region near the intersection of the one gate line and the one data line, the thin film transisor having a source electrode, a gate electrode and a drain electrode;

a protrusion extending from the common line; and

a liquid crystal layer interposed between the first and second substrates.

33. The liquid crystal display device of claim 32, wherein at least one of said gate lines comprises a first gate line layer and a second gate line layer.

- 34. The liquid crystal display device of claim 32, wherein the common line comprises a first common line layer and a second common line layer.
- 35. The liquid crystal display device of claim 34, wherein the protrusion extends from the first common line layer.
- 36. The liquid crystal display device of claim 32, wherein the protrusion is a quadrilateral shape.
- The liquid crystal display device of claim 36, wherein the protrusion is a square shape.
- 38. The liquid crystal display device of claim 32, wherein the protrusion includes an aperture in a central portion thereof.
  - 39. The liquid crystal display device of claim 32, further comprising an aperture in the protrusion.
  - 40. The liquid crystal display device of claim 35, wherein the second common line layer is on the first common line layer.
  - 41. The liquid crystal display device of claim 33, wherein the first gate line layer comprises aluminum.

- 42. The liquid crystal display device of claim 33, wherein the second gate line layer comprises a metal selected from a group consisting of molybdenum (Mo), choromium (Cr) and tungsten (W).
- 43. The liquid crystal display device of claim 34, wherein the first common line layer comprises aluminum.
- 44. The liquid crystal display device of claim 34, wherein the second common line layer comprises a metal selected from a group consisting of molybdenum (Mo), choromium (Cr) and tungsten (W).
- 45. The liquid crystal display device of claim 32, further comprising an etching hole over a portion of the protrusion.

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46. The liquid crystal display device of claim 38, further comprising an etching hole over the aperture.